

ABSTRACT

The present invention has a purpose of providing a tube connecting apparatus capable of stably, accurately executing control of wafer temperature even when connecting of tubes is conducted continuously. A
5 tube connecting apparatus (1) includes a heater (70) for heating a wafer holder (5a), a thermister (71) which detects the temperature of the wafer holder (5a), a heater heating control device (69) which controls the heater (70) based on output of the thermister (71), and a wafer heating control
10 power control. Before the start of heating the wafer (6) by the wafer heating control device (68), the control of the heater (70) is performed by the heater heating control device (69) for temperature control so that the wafer holder (5a) is heated to a fixed temperature (about 65°C).